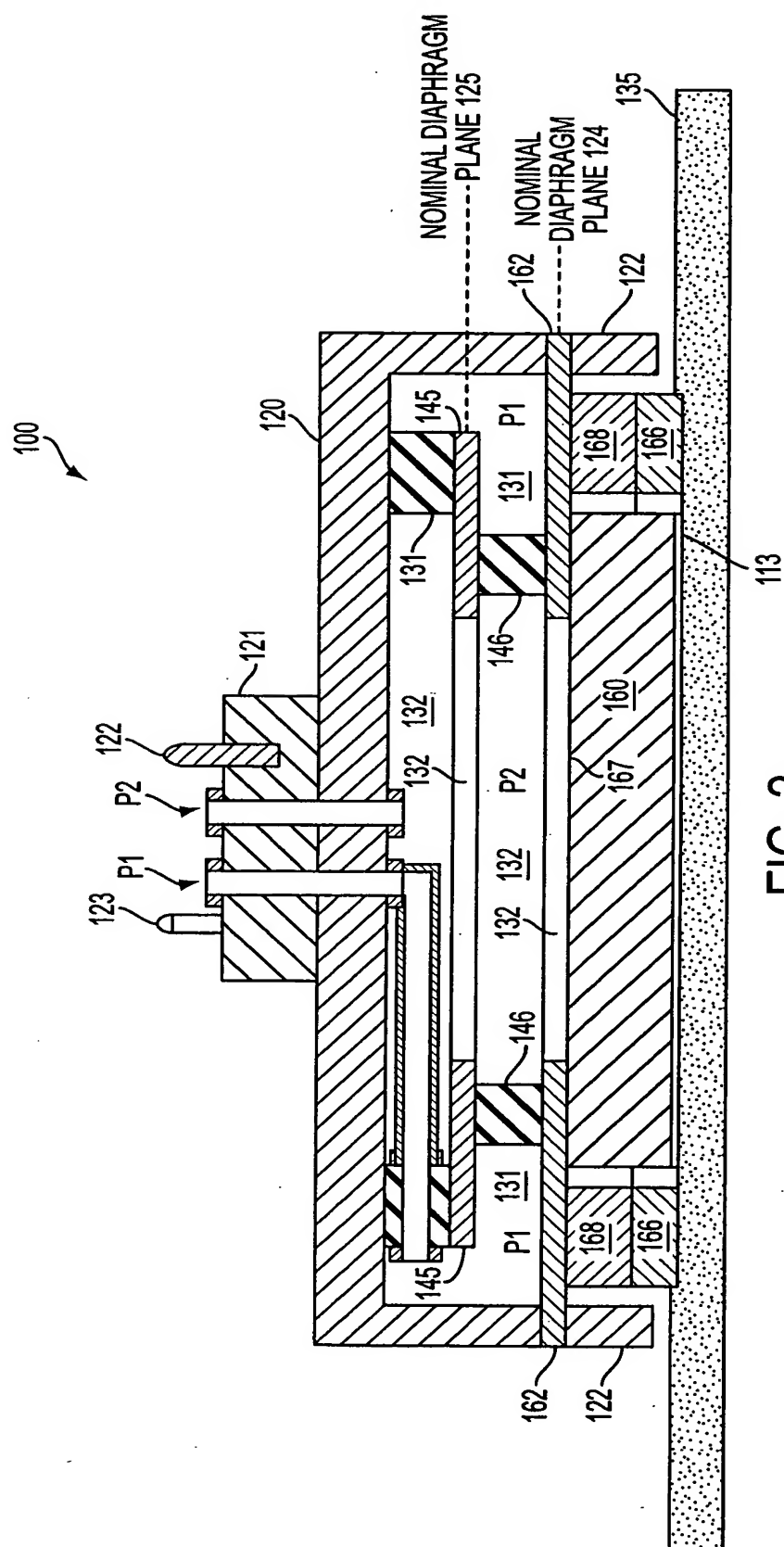


FIG. 1



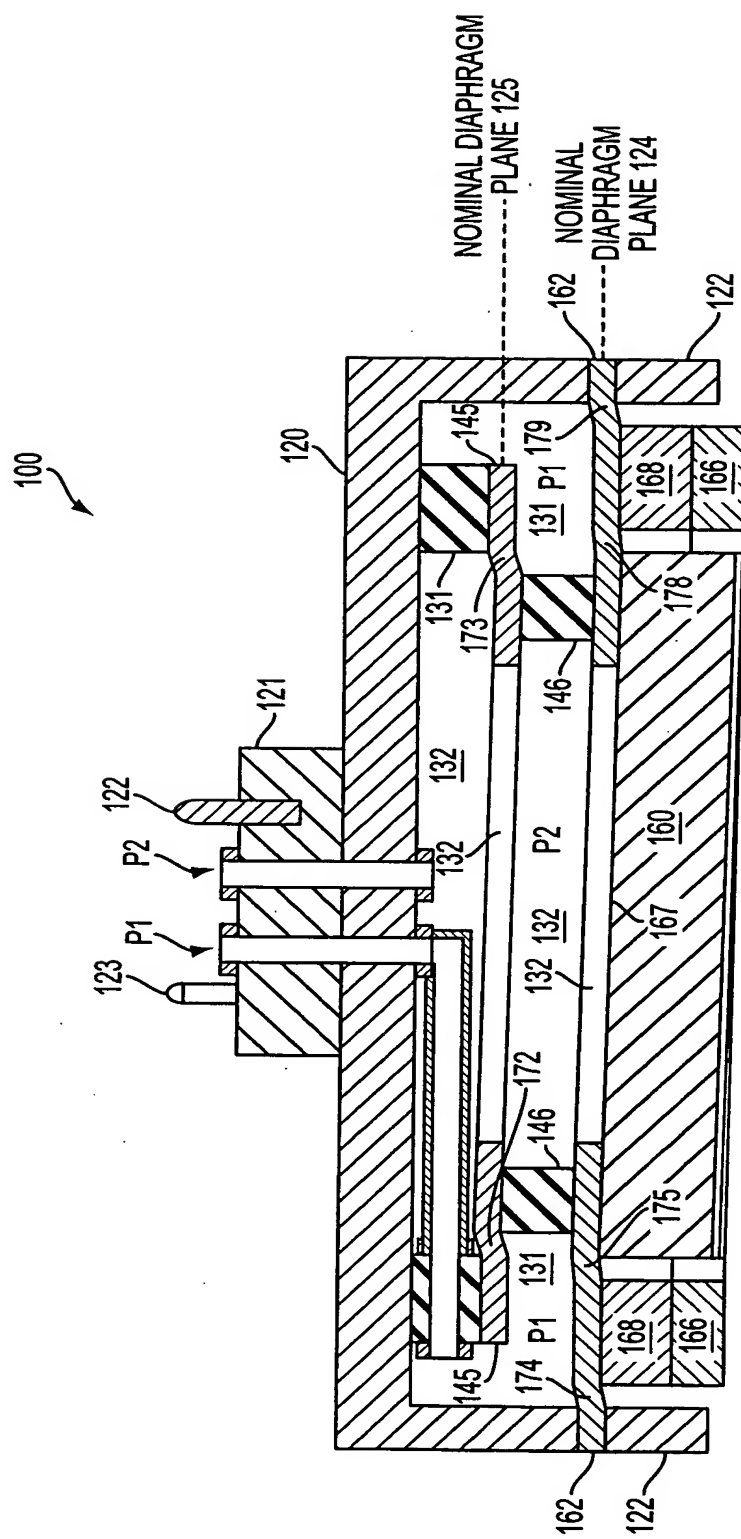


FIG. 3

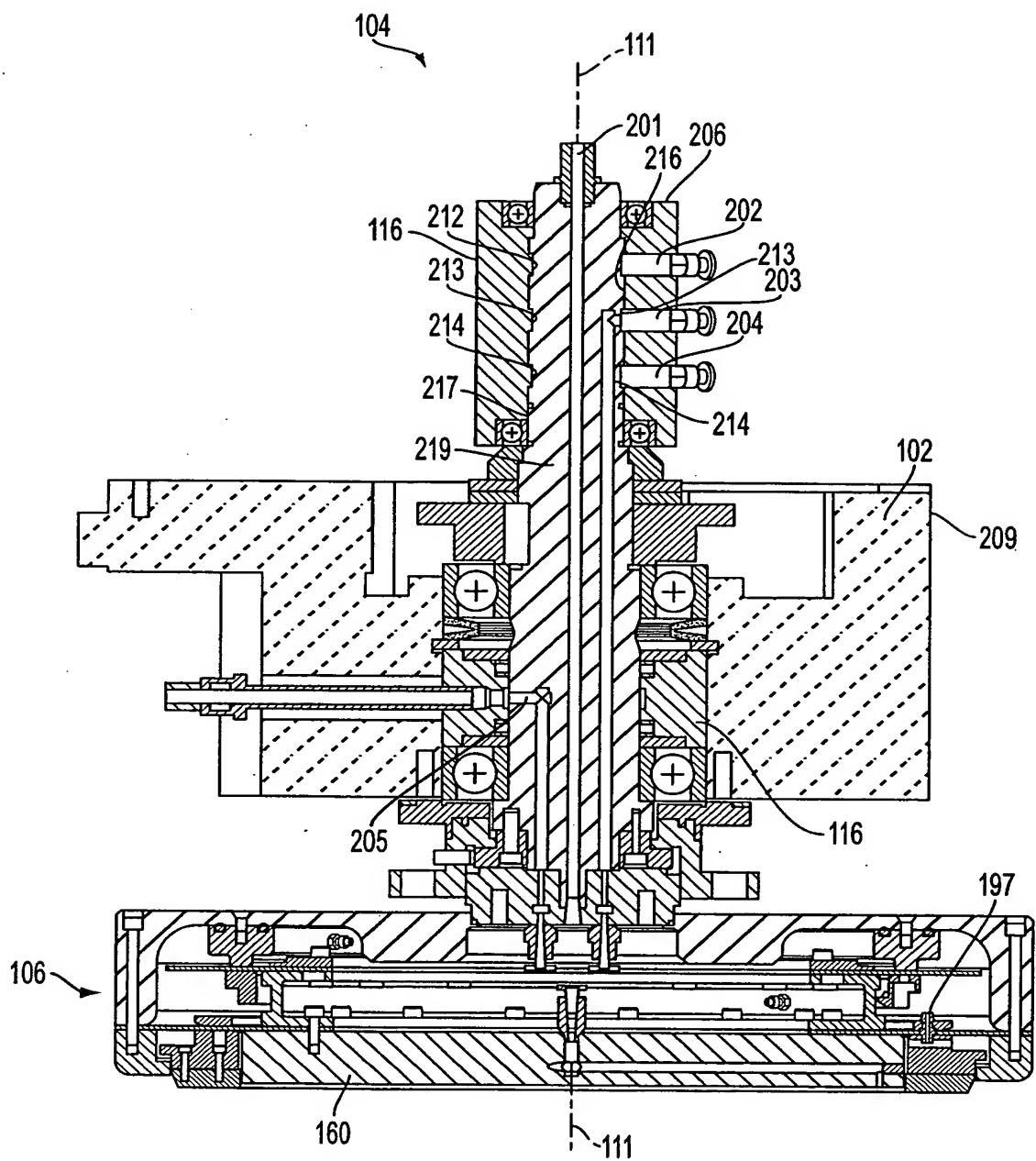


FIG. 4

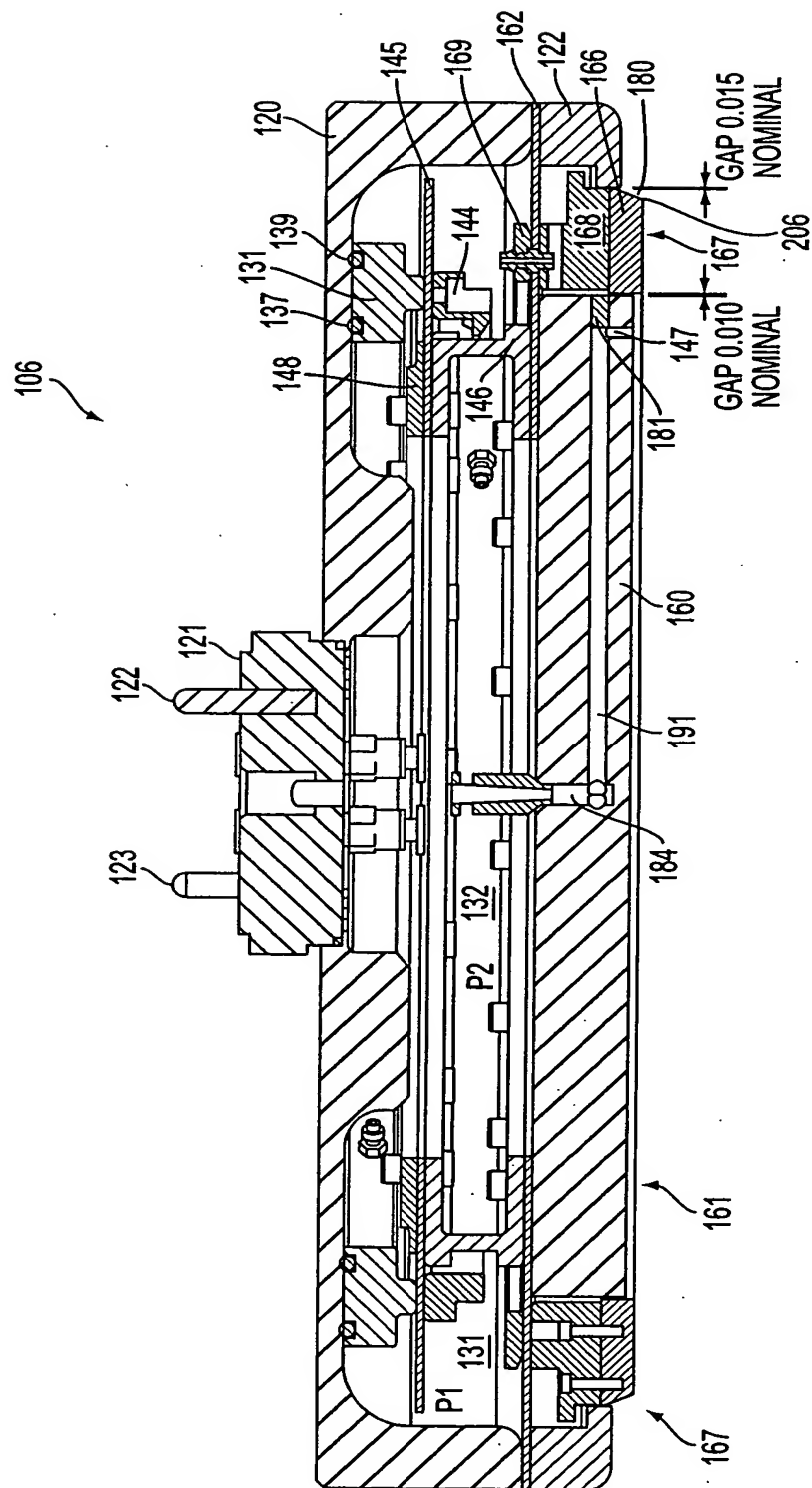


FIG. 5

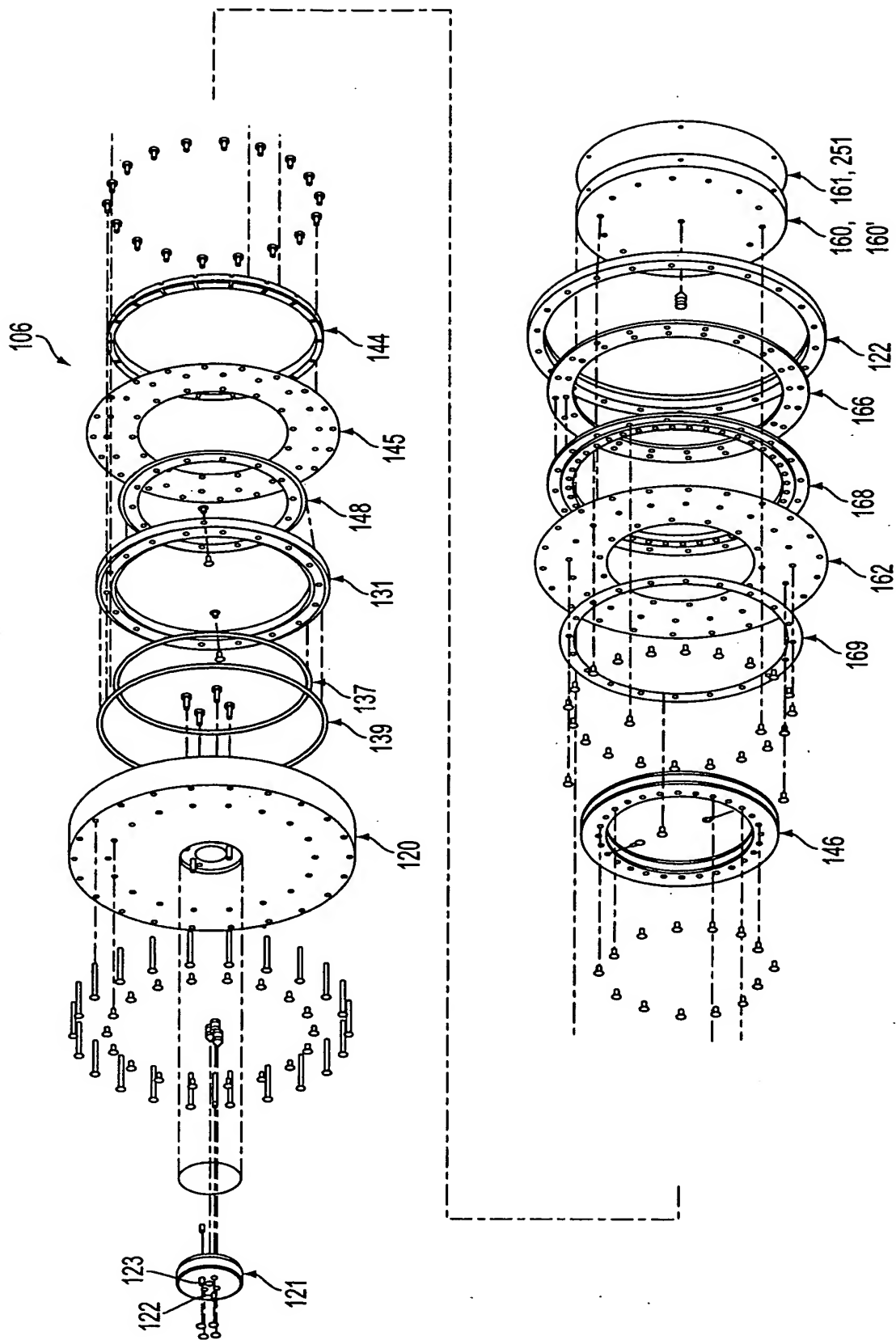


FIG. 6

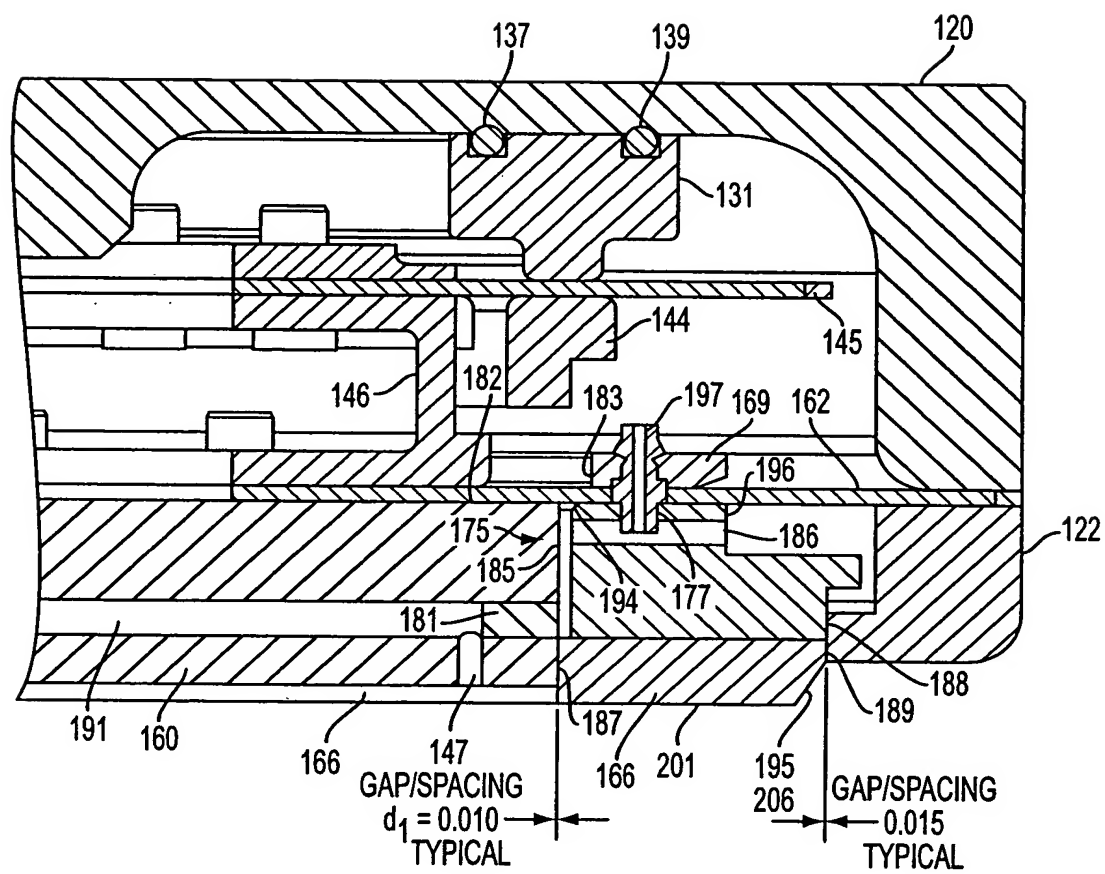


FIG. 7

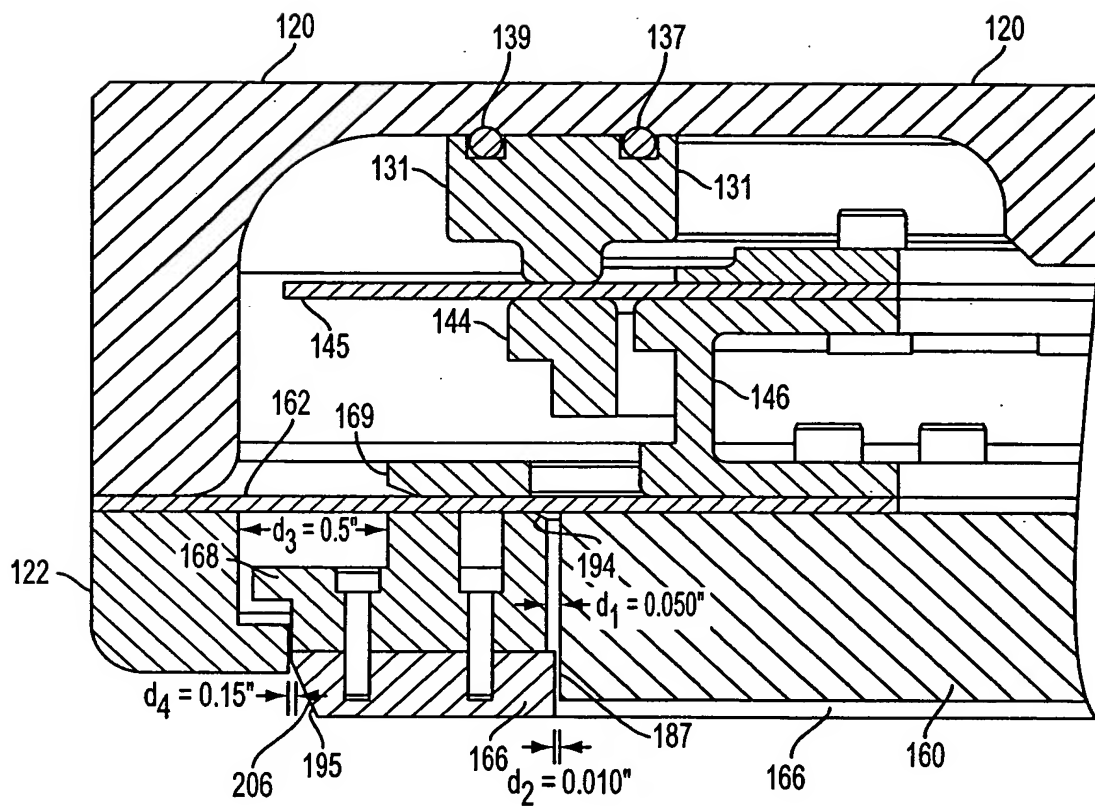
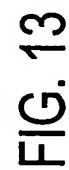
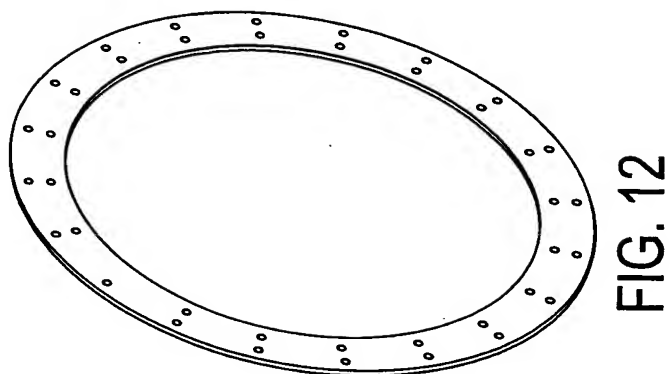
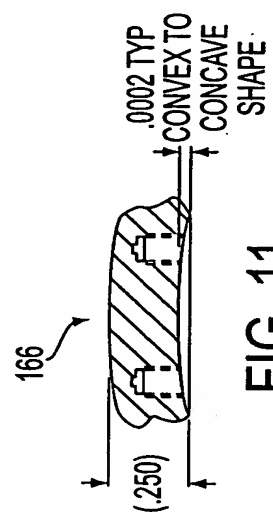
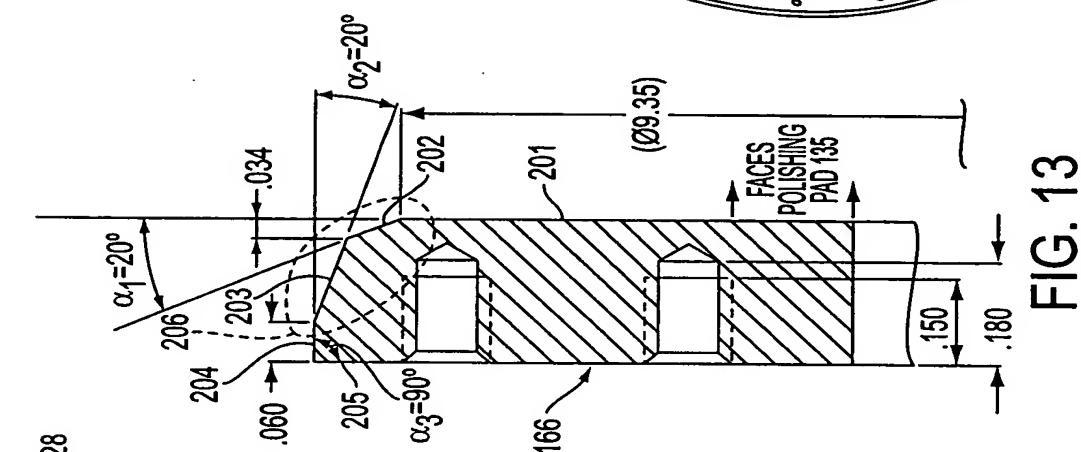
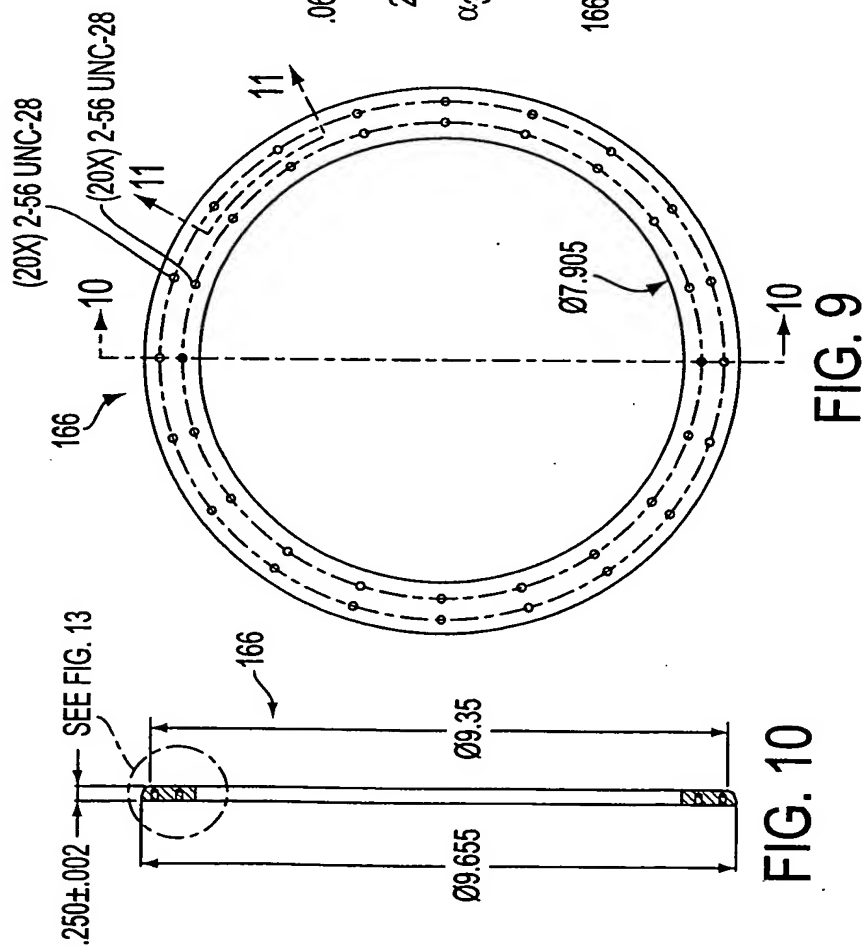
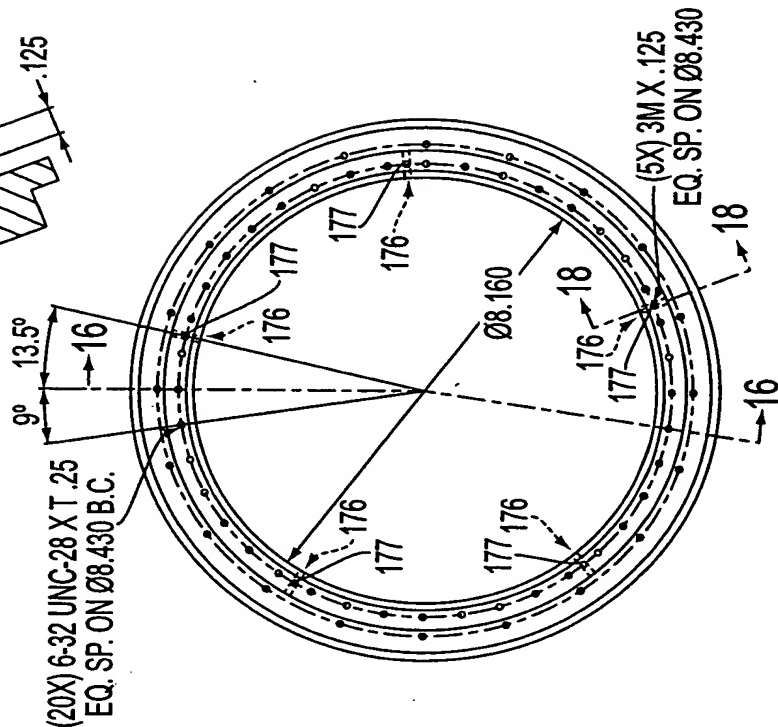
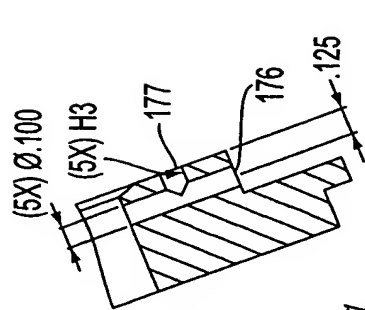
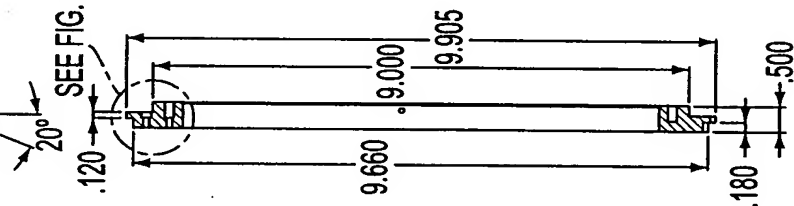
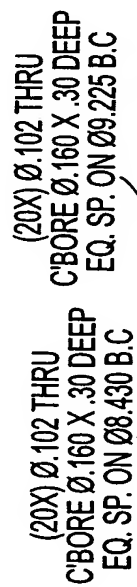


FIG. 8





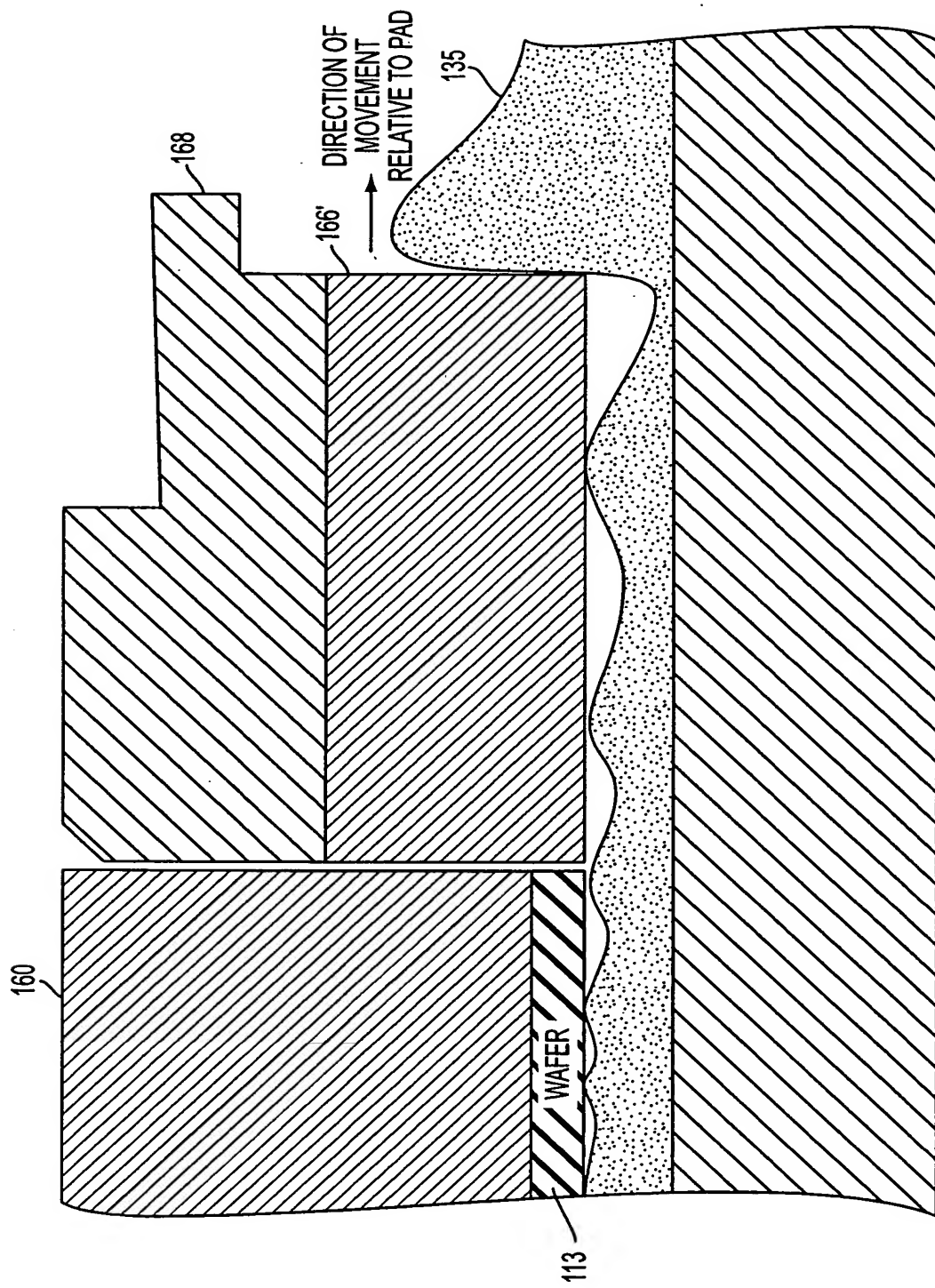


FIG. 19

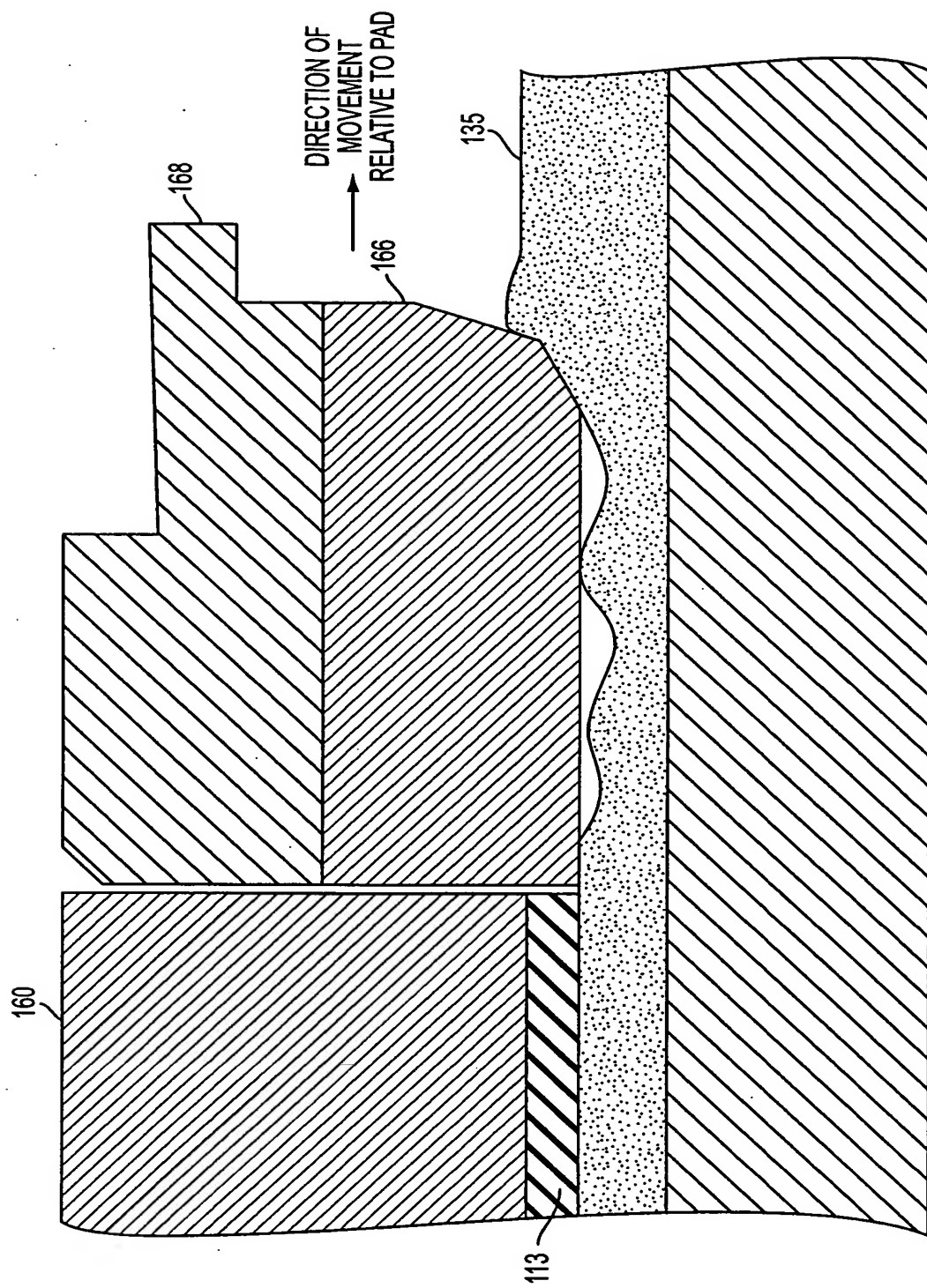


FIG. 20

WAFER LOADING PROCEDURE

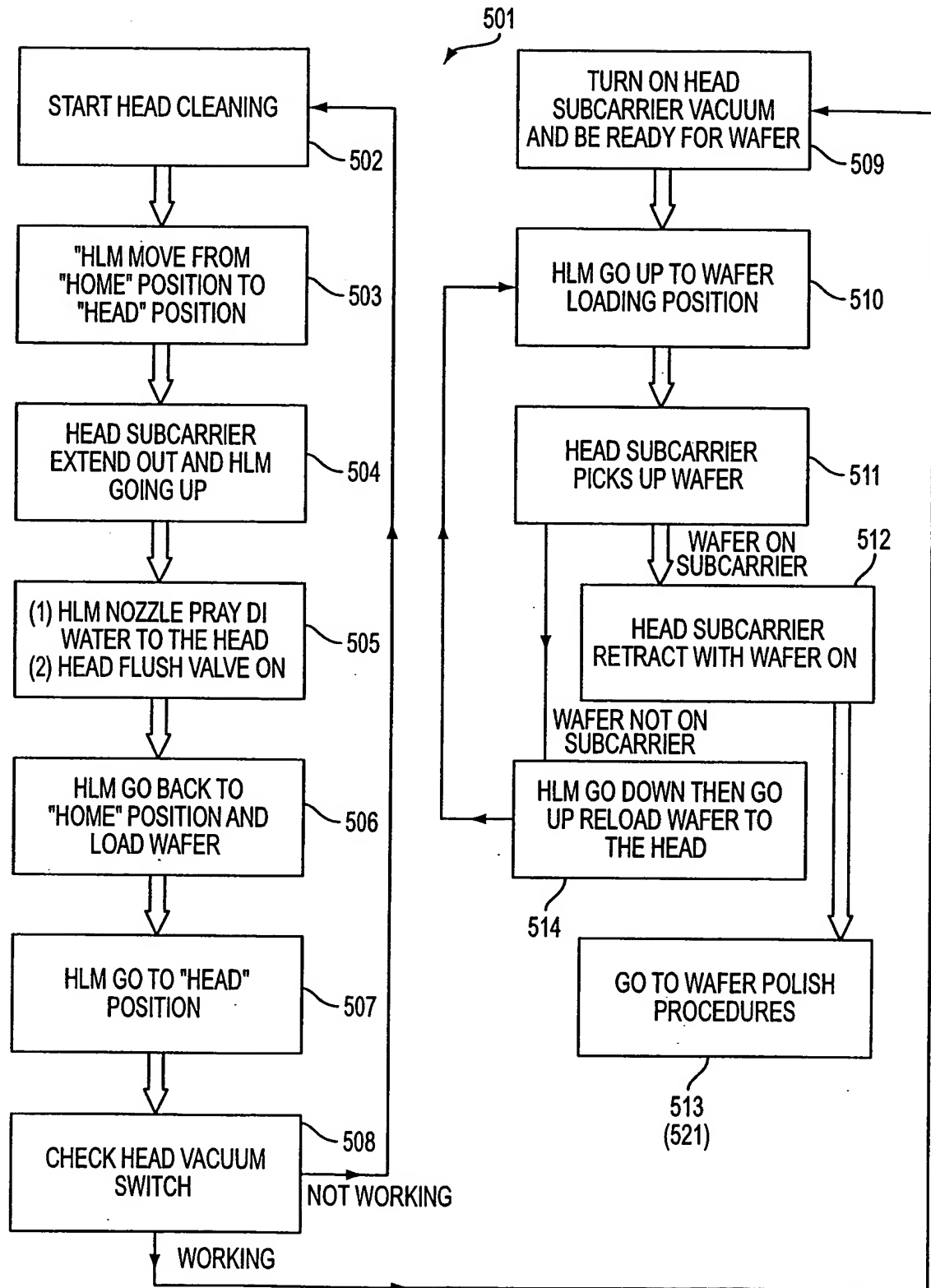
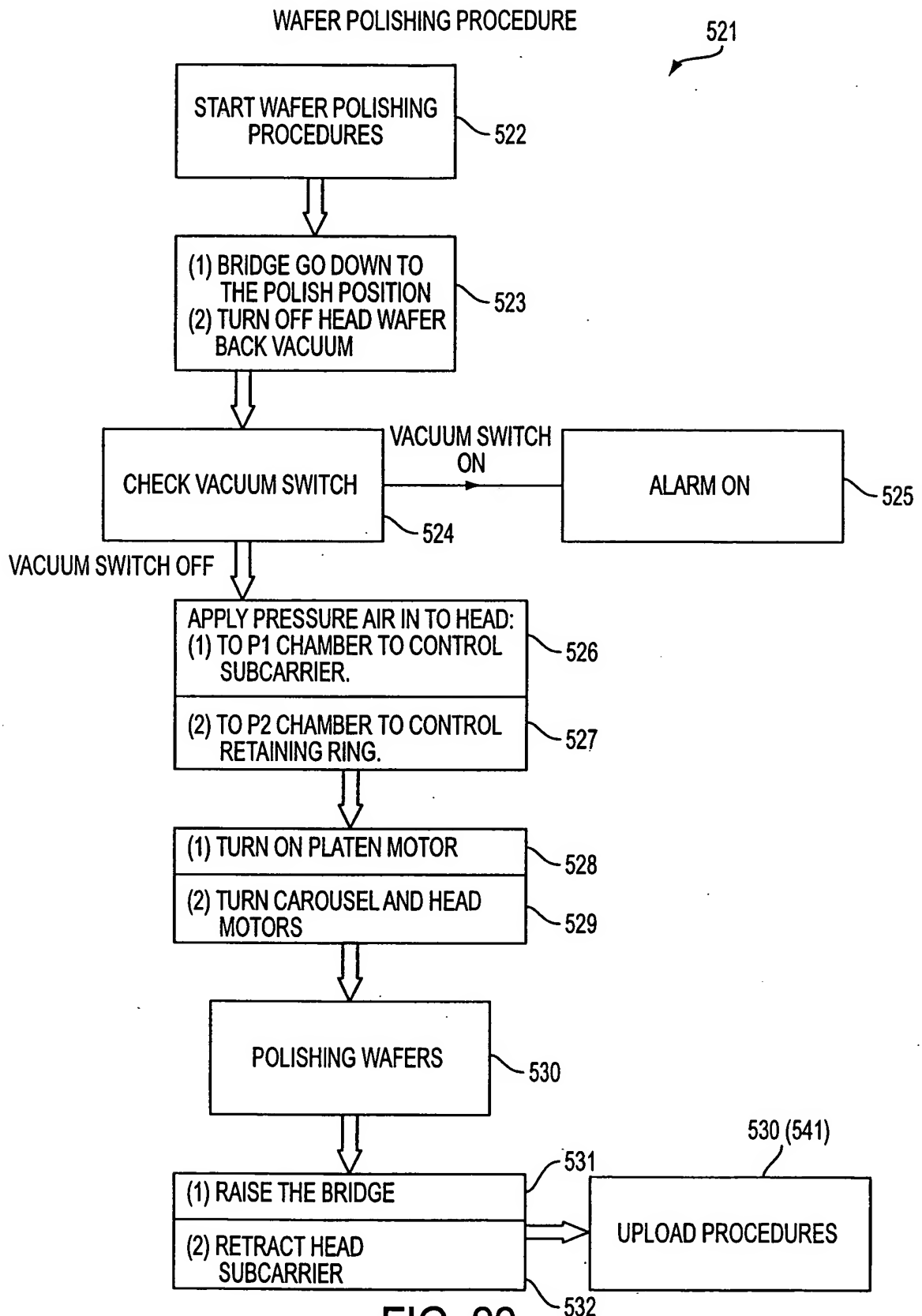


FIG. 21



WAFER UNLOAD PROCEDURE

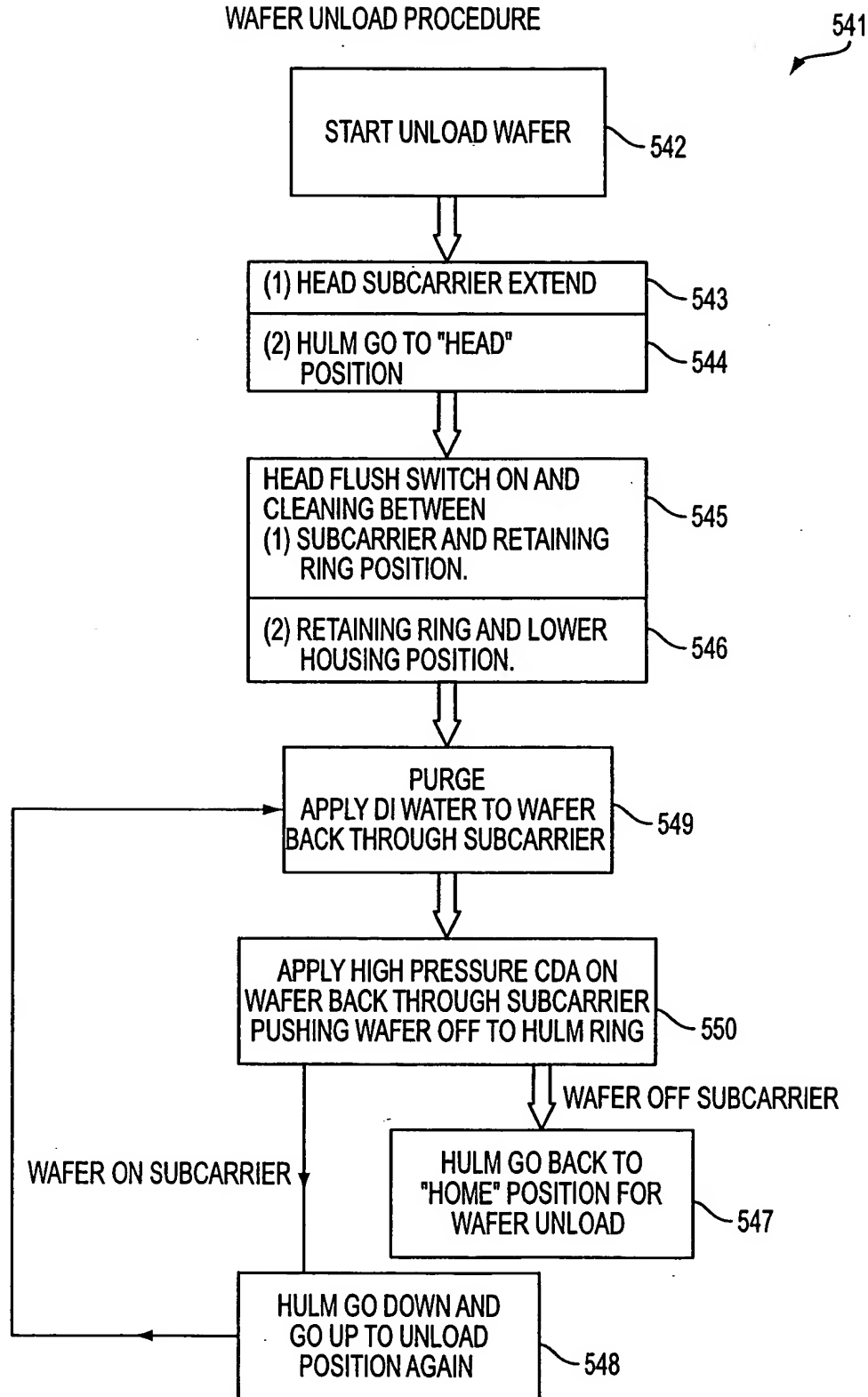


FIG. 23